Record Nr. UNINA9910818774003321 CMOS nanoelectronics: innovative devices, architectures, and **Titolo** applications / / edited by Nadine Collaert Pubbl/distr/stampa Singapore:,: Pan Stanford Pub.,, 2013 **ISBN** 0-429-11283-1 981-4364-03-7 Descrizione fisica 1 online resource (444 p.) Altri autori (Persone) CollaertNadine Disciplina 621.3815 Soggetti Molecular electronics Nanotechnology Lingua di pubblicazione Inglese **Formato** Materiale a stampa Livello bibliografico Monografia Note generali Description based upon print version of record. Includes bibliographical references. Nota di bibliografia Front Cover; Contents; Preface; I. Integration of Multi-Gate Devices Nota di contenuto (FinFET); 1. Introduction to Multi-Gate Devices and Integration Challenges; 2. Dry Etching Patterning Requirements for Multi-Gate Devices: 3. High-k Dielectrics and Metal Gate Electrodes on SOI MuGFETs; 4. Doping, Contact and Strain Architectures for Highly Scaled FinFETs; II. Circuit-Related Aspects; 5. Variability and Its Implications for FinFET SRAM; 6. Specific Features of MuGFETs at High Temperatures over a Wide Frequency Range; 7. ESD Protection in FinFET Technology; III. Exploratory Devices and Characterization Tools 8. The Junctionless Nanowire Transistor9. The Variational Principle: A Valuable Ally Assisting the Self-Consistent Solution of Poisson's Equation and Semi-Classical Transport Equations; 10. New Tools for the Direct Characterisation of FinFETS; 11. Dopant Metrology in Advanced FinFETs Sommario/riassunto This book covers one of the most important device architectures that have been widely researched to extend the transistor scaling: FinFET. Starting with theory, the book discusses the advantages and the integration challenges of this device architecture. It addresses in detail

the topics such as high-density fin patterning, gate stack design, and source/drain engineering, which have been considered challenges for the integration of FinFETs. The book also addresses circuit-related aspects, including the impact of variability on SRAM design, ESD